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OTHER RE	FERENC	ES (Including Author, Title	, Date, Pertinent I	Pages, Etc.)					
		Iwamoto, N. E. "Applying Polymer Process Studies Using Molecular Modeling". Proceedings of the 4th International							
MF	00	Conference on Adhesive Joining and Coating Technology in Electronics Manufacturing (Adhesives in Microelectronics							
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MF	PP	50 <sup>th</sup> Electronic Components and Technology Conference; May 21-24, 2000; Las Vegas, NV. Pp. 1354-1359							
MF	QQ	Iwamoto, N.E. "Simulating Stress Reliability Using Molecular Modeling Methodologies". 32 <sup>rd</sup> International Symposium on Microelectronics; Chicago, III; October 26-28, 1999, Proceedings pp. 415-420.							
EXAMINER	<del></del>	<u> </u>		DAT	E CONSIDERED				
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\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 60%; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.